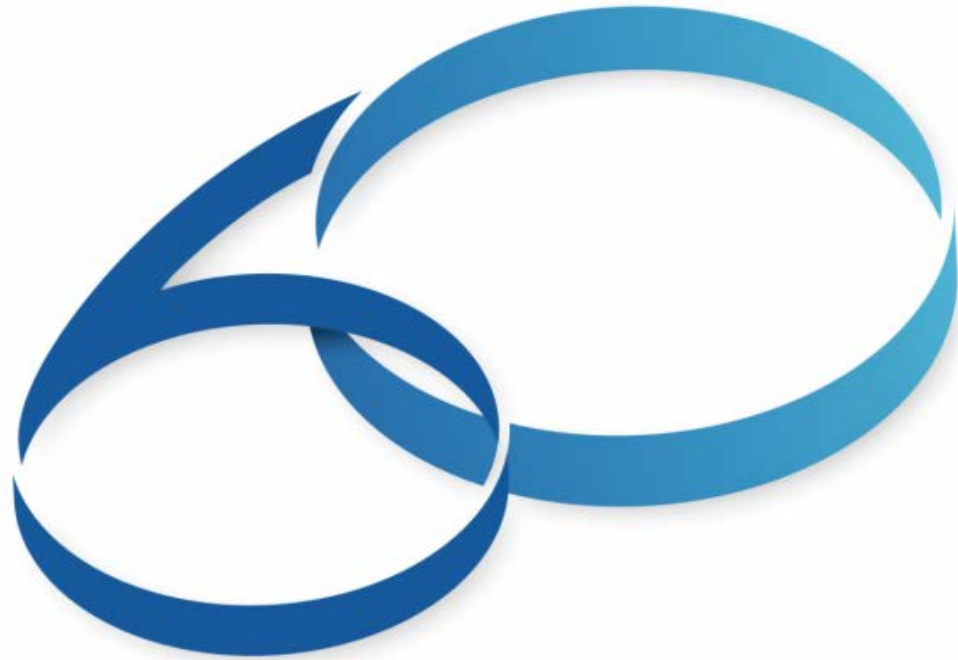


SPAIN @ CERN

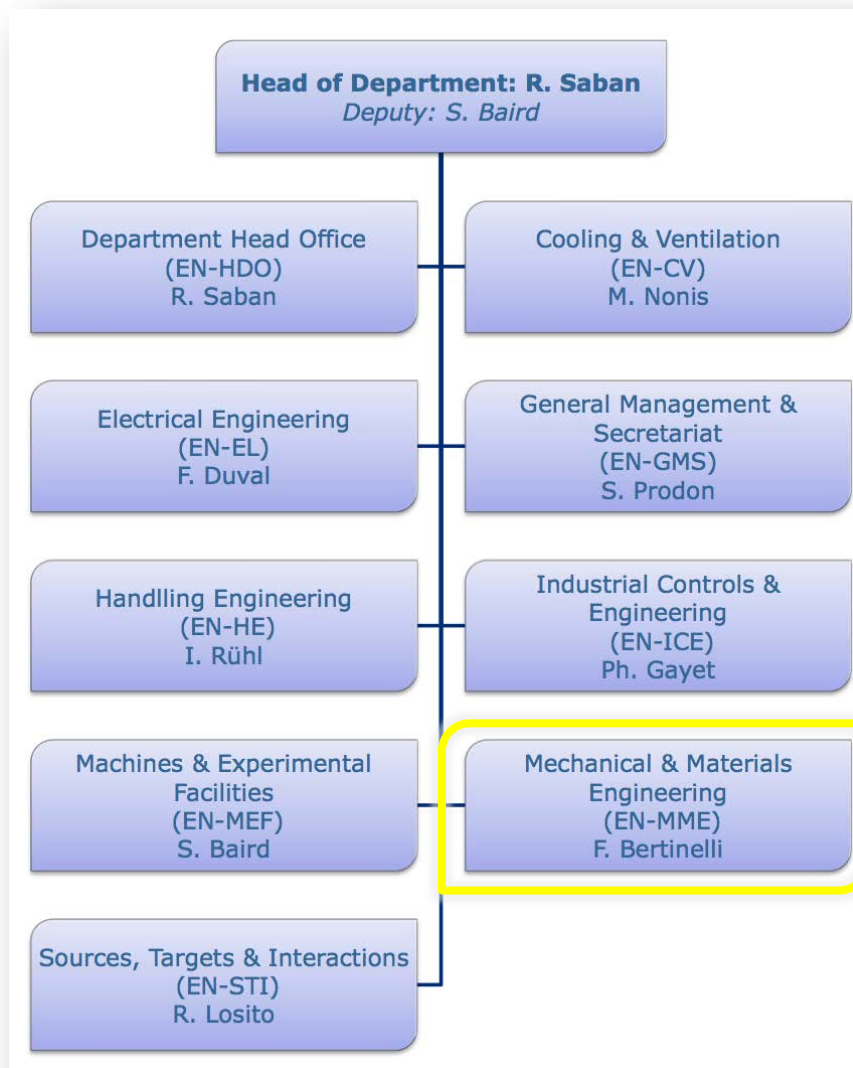
27/10/2014 – CERN Geneva



YEARS/ANS **CERN**

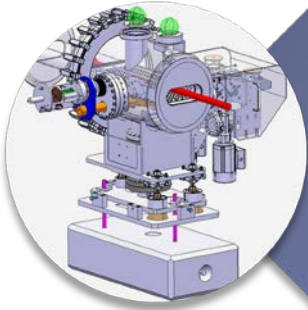
A. Dallocchio on behalf of the EN-MME-FS section

Engineering Dept. Structure



- Infrastructures
- Engineering
- Coordination
- Production

EN-MME: Mechanical & Materials Engineering Group



Engineering & Design

- Design Office:
 - 40 designers and engineers
 - CATIA / SmarTeam, ANSYS, LS-Dyna...
- Experimental Mechanics Lab.



Production

- Mechanical workshop (4000 m²):
 - 50 technicians and engineers
 - CNC machining
 - Assembly & metal forming
 - Welding (TIG, MIG, electron beam, laser, vacuum brazing)
- **Technical Subcontracting Service**



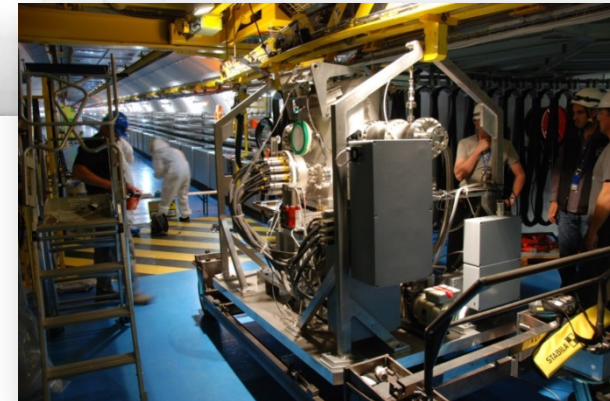
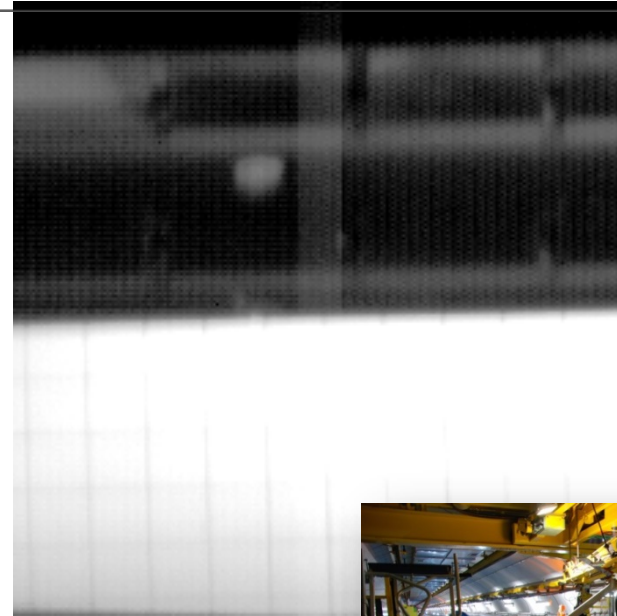
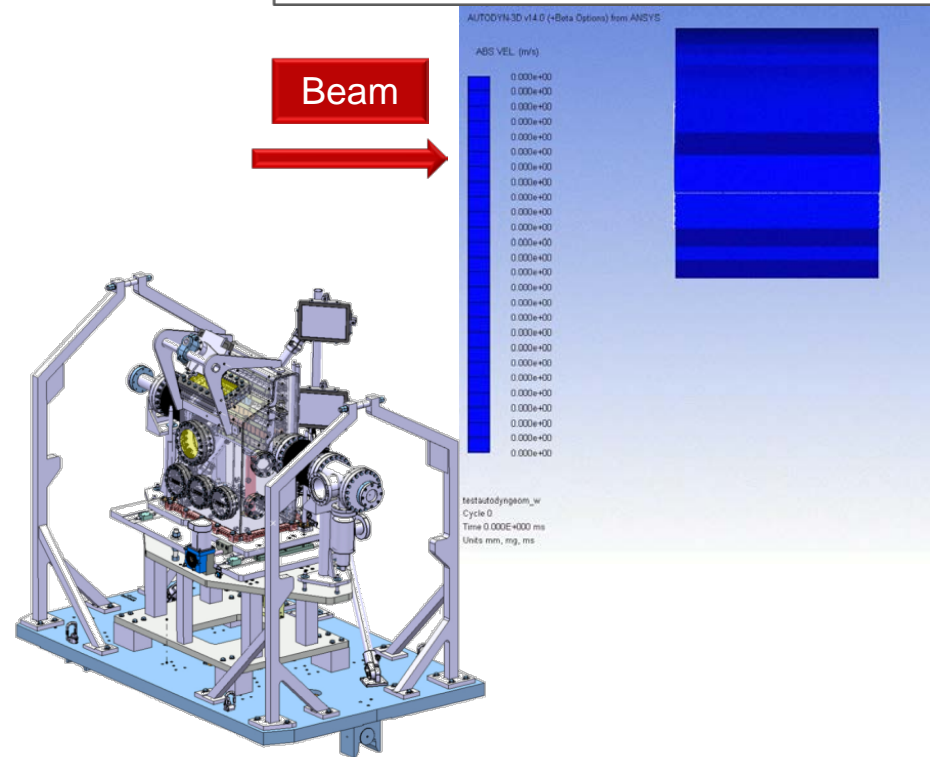
Materials & Metrology

- Material science consultancy:
 - metallurgical analyses, microscopy, mechanical tests
- NDT: US, radiography, tomography
- Metrology: 350 m² lab. equipped with CMM.

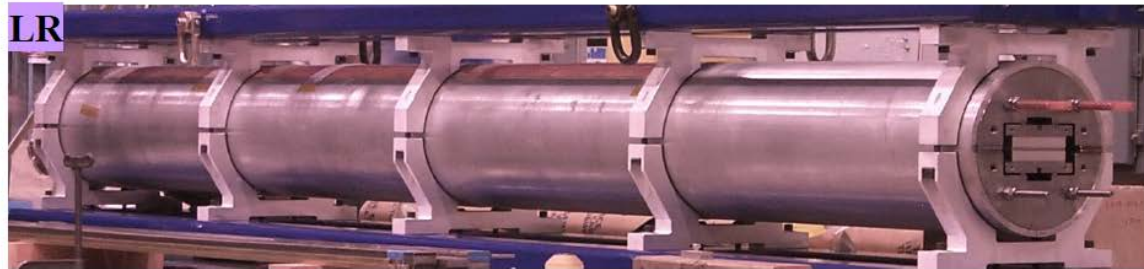
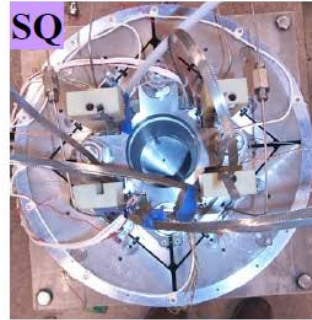
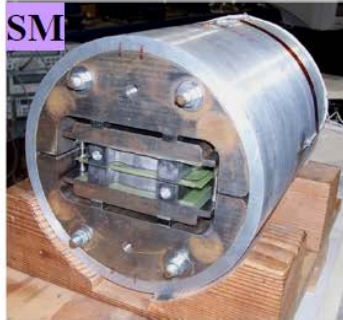
EN-MME Mandate:

The mandate of the MME group is to provide to the CERN community specific engineering solutions combining mechanical design, production facilities and material sciences. This group owns, maintains and develops the 30 years old know-how on the mechanical construction of beam accelerators and physics detectors.

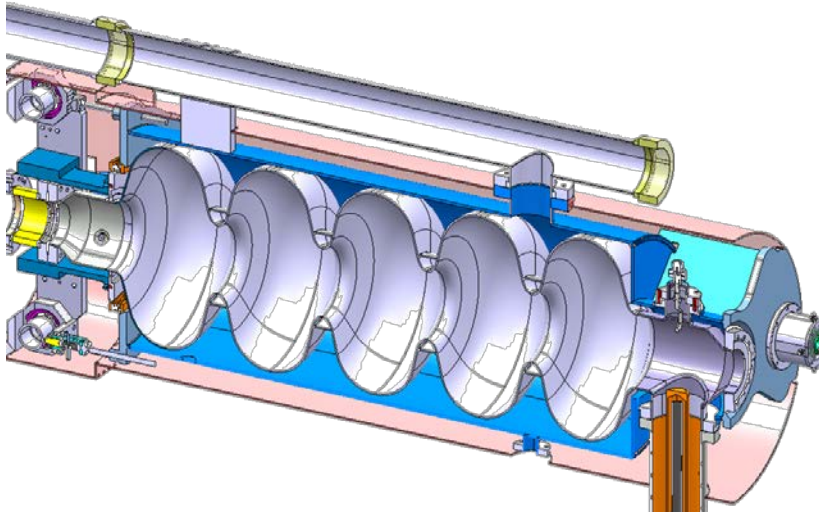
Particle Beam Impact : comparison between simulation and experiment



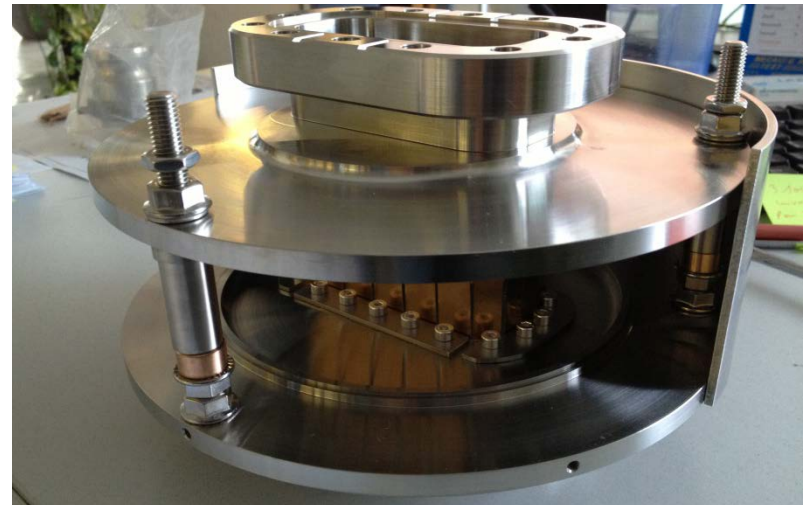
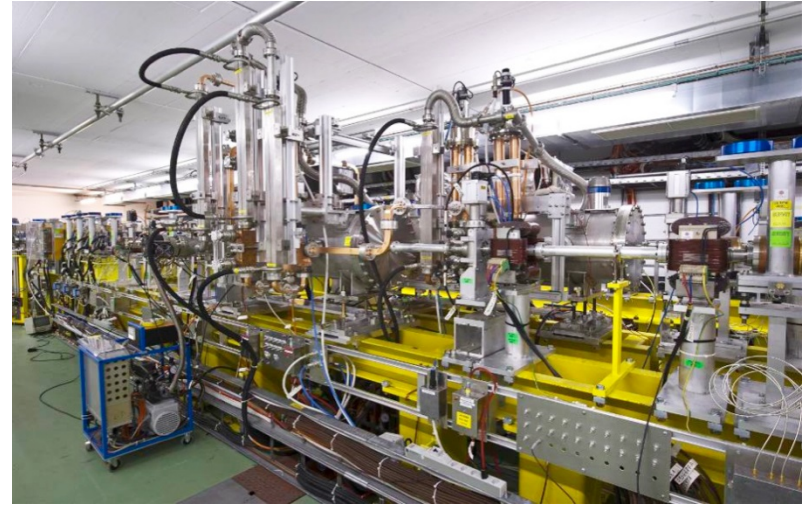
Superconducting Magnets



Superconducting RF Cavities



Beam Lines



Warm RF Cavities

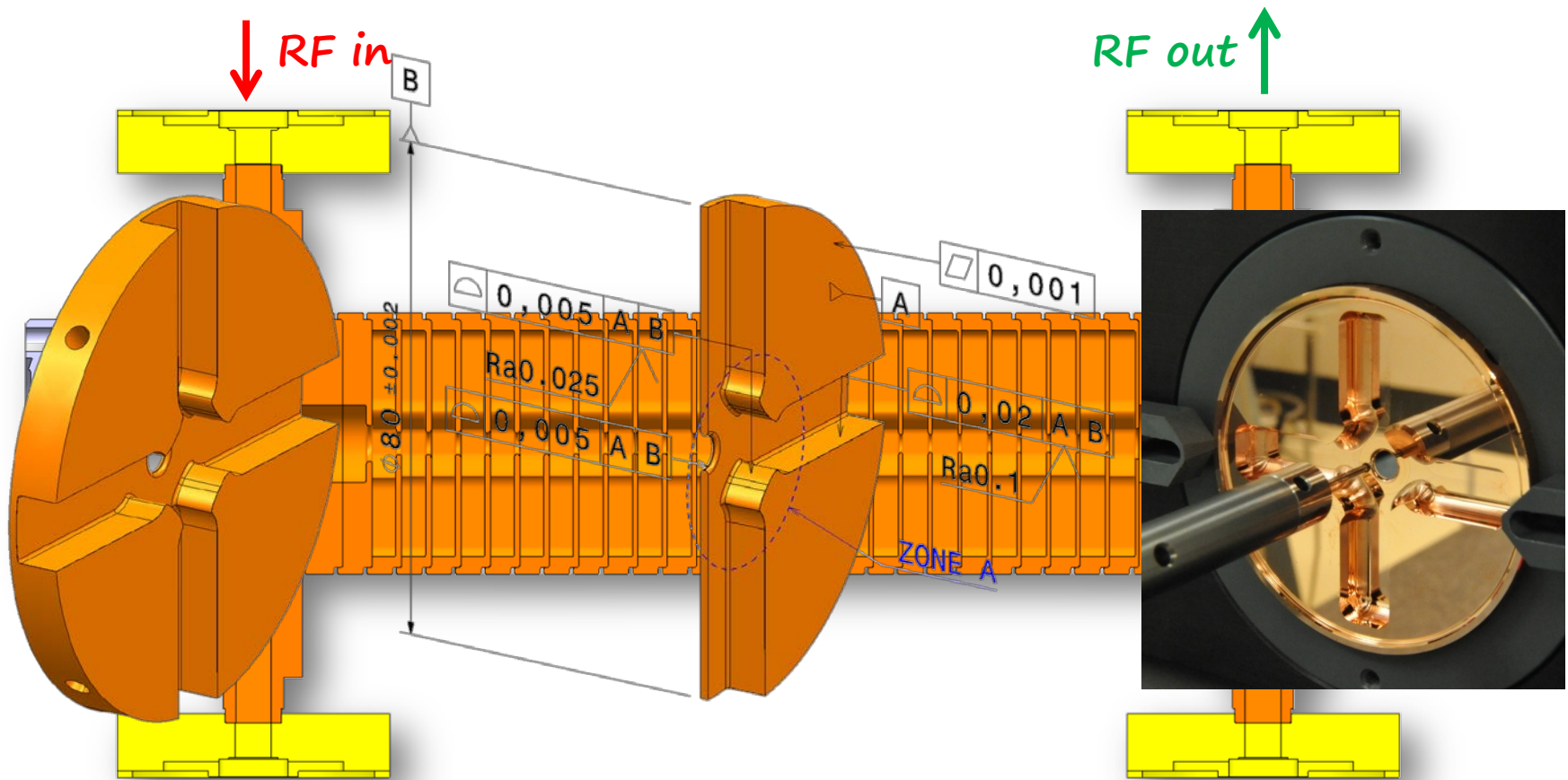


Vacuum Chambers



CLIC

The design involves coupled RF cavities to transfer energy from a high-current, low-energy drive beam to a low-current, high-energy beam to be used in collisions.



MME Subcontracting Service:

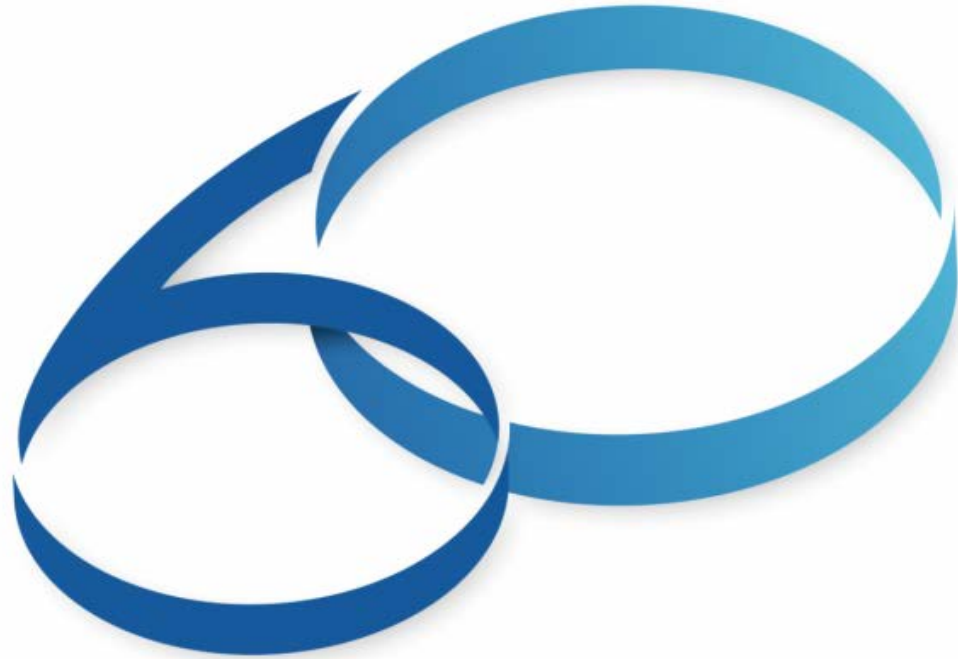
~1000 contracts/year in close collaboration with FP Dept.

		<i>Réels</i>	<i>Réels</i>	<i>Réels</i>	<i>Réels</i>		<i>Estimés</i>
		Facturé 2010	Facturé 2011	Facturé 2012	Facturé 2013		Charge restante 14/01/2014
<i>Activités de:</i>							
Bureau d'Etudes	(MCHF)	2.4	2.7	3.1	2.8		1.8
Soustraitance	(MCHF)	3.8	5.9	7.0	7.9		5.7
Fabrication	(MCHF)	2.6	3.5	4.3	5.7		3.7
Totale	(MCHF)	8.8	12.1	14.4	16.4		11.2

MME Subcontracting Service: what kind of company are we looking for?

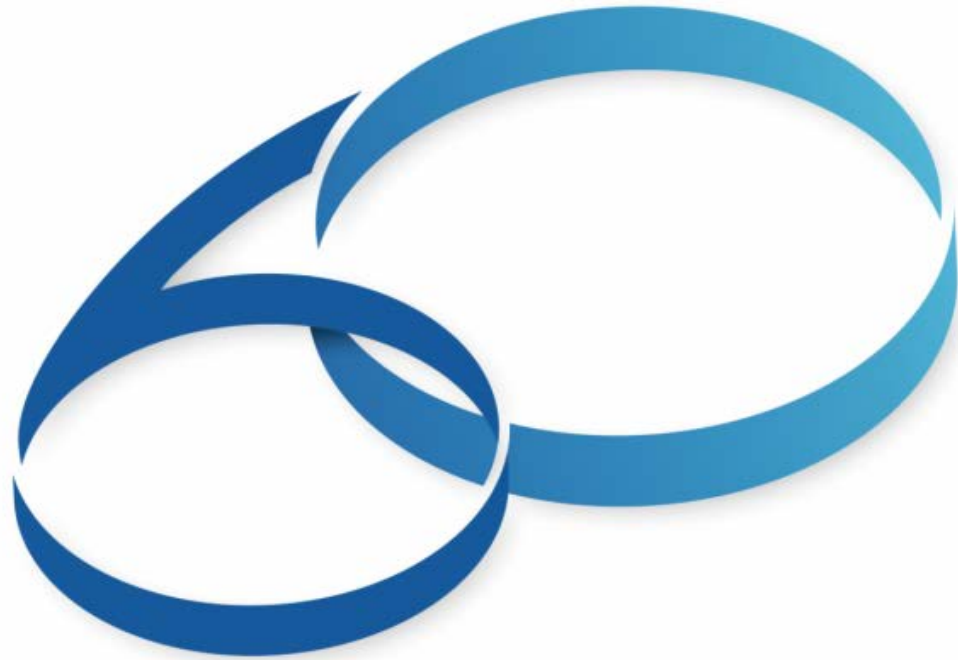
Sector	Main products	Tecnology
UHV-XHV (Vacuum)	Vacuum chambers; Flanges	TIG welding; EB welding; Vacuum Brazing
UHV-XHV (Vacuum)	Bellows;	TIG welding; EB welding;
General machining	Frame (construction steel, stainless steel and aluminium)	Welding (at least 3 meter long) Milling Painting
Precision machining (+/- 0.02)	Machined parts (construction steel, stainless steel and aluminium; Cu alloys)	Milling, turning, grinding (500x500x500mm)
Sheet metal forming		Cutting (laser, water, plasma) Welding Bending
Ceramic	Aluminium Oxide Zirconium Oxide Silicon Carbide Silicon Nitride	Machining Surface treatment
Machining	Exotic materials (tantalum, tungsten,molybdenum, carbon)	Milling, turning, grinding

Thank you for your attention



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Back-up Slides



YEARS/ANS **CERN**

CERN Procurement Guidelines

<u>Requests up to 1 kCHF</u>	<ul style="list-style-type: none"> •1 bid by Technical Officer •<u>Purchase Requisition (DAI)</u>
<u>Requests between 1 and 5 kCHF</u>	<ul style="list-style-type: none"> •1 written bid by Technical Officer •<u>Purchase Requisition (DAI)</u> •Validated by Procurement Officer
<u>Requests between 5 and 10 kCHF</u>	<ul style="list-style-type: none"> •Price enquiry by Technical Officer or Procurement Officer •Minimum of 3 bids requested •<u>Purchase Requisition (DAI)</u> made to the lowest compliant bidder
<u>Requests between 10 and 50 kCHF</u>	<ul style="list-style-type: none"> •Technical specification provided by Technical Officer •Price enquiry made by Procurement Officer •3 to 5 bids requested •<u>Purchase Requisition (DAI)</u> made to the lowest compliant bidder
<u>Requests between 50 and 200 kCHF</u>	<ul style="list-style-type: none"> •Departmental Request •Price enquiry by Procurement Officer •3 to 5 bids requested •<u>Purchase Requisition (DAI)</u> made to the lowest compliant bidder
<u>Requests between 200 and 750 kCHF</u>	<ul style="list-style-type: none"> •Departmental Request •Market Survey followed by Invitation to Tender
<u>Requests above 750 kCHF</u>	<ul style="list-style-type: none"> •Departmental Request •Market Survey followed by Invitation to Tender •Finance Committee approval

CLIC

Rough-machining

Pre-turning + 100 μm

Pre-milling + 100 μm

Tuning holes

Stress relief $\sim 245\text{ }^\circ\text{C}$ (optional)

Finish milling + 10 μm

Finish turning + 10 μm

Stress relief $\sim 245\text{ }^\circ\text{C}$ (optional)

UP-machining:

Mounting of vacuum fixing

UP-turning of the support

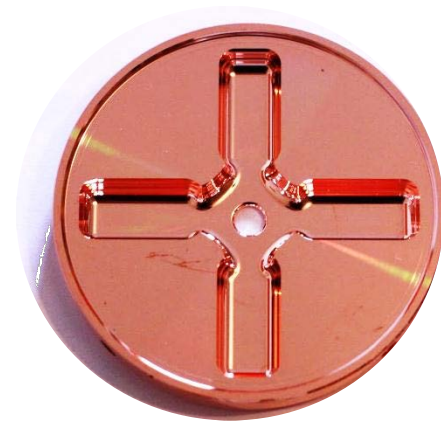
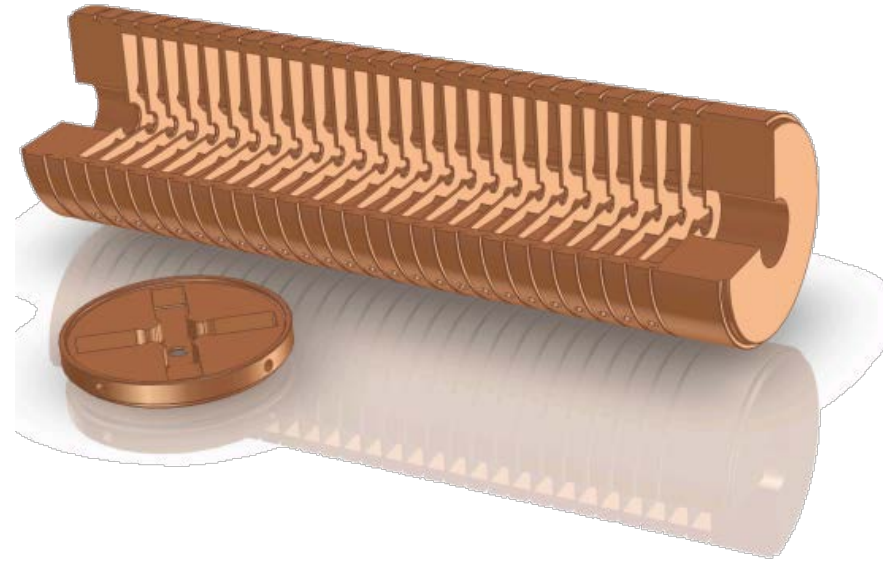
Alignment

UP-turning ref. plan A

UP-turning opposite side

Wave guide pocket UP milling

Iris final turning (requested up to the nose)



NOTES:

1. Dimensions in this drawing are at 20°C in free state.
2. Lubricant based on Chlorine or Sulfur should be avoided.
No polishing is allowed.
3. No deformations admissible due to stress release or shocks during and after machining.
4. The product should be marked with present drawing number/column N from the table, example CLIATCAS0059/1.
5. To be protected against scratches and marks of any nature, burrs are not allowed.
6. The product must be individually packed inside a main delivery box.
7. * - Evaluation length is equal to $(t-2*be)$ mm.
8. Roughness is according to ISO 1302.
9. The step up to 0.005 mm between milled and turned zones is allowed.

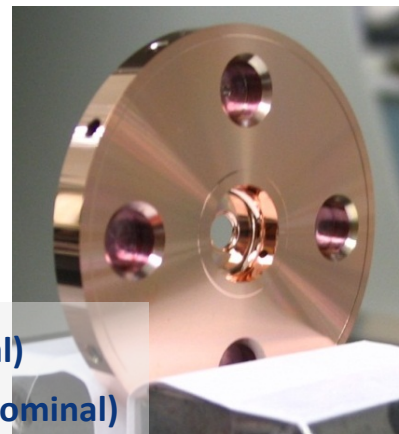
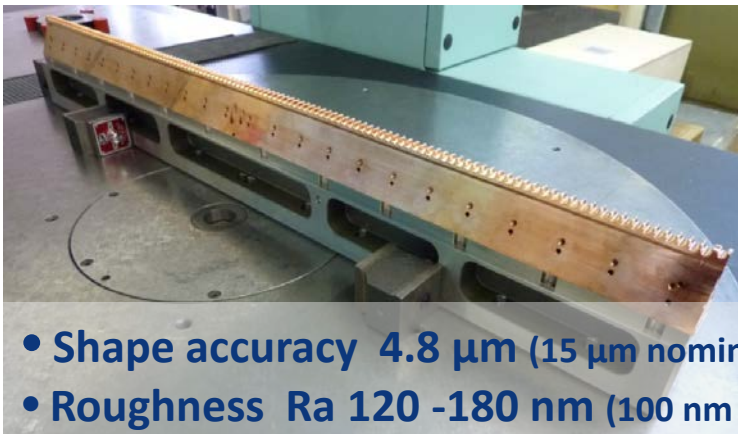
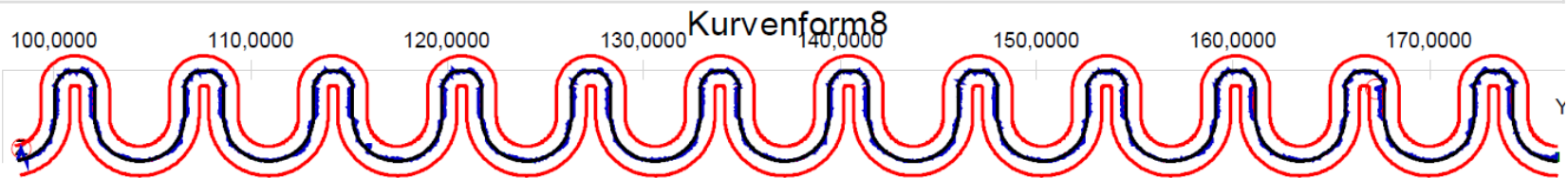
What kind of company CLIC needs

Diamond machining (turning and milling). Companies owners of an ultra-precision combined (TURNING+MILLING) machine like Precitech, Moore-Nanotech, LT- ULTRA will be preferred.

Tight tolerances: roughness of 25nm and shape accuracy of 5 μ m (companies used to machine optical components should be able to reach the required tolerances)

NB: Polishing is not allowed.

High accuracy CMM machine with MPE less than 1 μ m. Contactless optical measurements. At the moment, we measure all the parts with a CMM of accuracy of 0.3+L/1000, but even if we use a low force head, we leave marks on the parts. We have to avoid an kind of marks on the parts.



- Shape accuracy 4.8 μ m (15 μ m nominal)
- Roughness Ra 120 -180 nm (100 nm nominal)

CLIC Metrology



Measuring Range

10.12.7 1200 x 1000 x 700 mm³

Accuracy (according to ISO 10360)

MPE E **0.3 + L/1000** μm

MPE P **0.4** μm

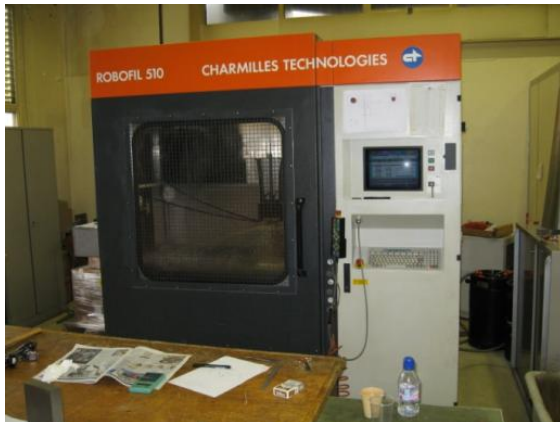
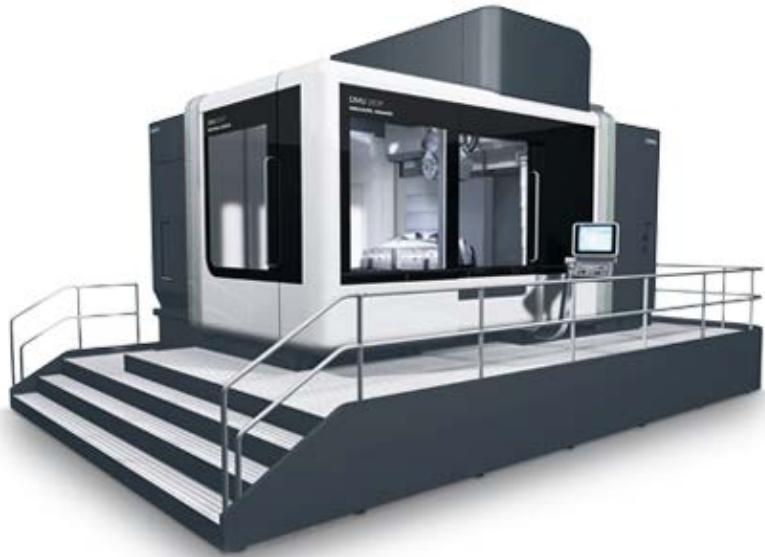
MPE THP 1.2 μm / 59s

Some References

- ▶ Modus, USA
- ▶ Sandia, USA
- ▶ Nano Precision Products, USA
- ▶ Bosch, Germany

Metrologic Principle:
“Closed frame - moving table”

MME Workshop



MME Metrology

CONTACT PROBE MACHINE

Ferranti

Olivetti

Leitz Infinity

OPTICAL PROBE MACHINE

Wegu

Mahr

PORTABLE 3D MEASURING ARM

Romer

ROUGHNESS – TOPOGRAPHY – PROFILE

MITUTOYO SJ 301 (Portable)

MITUTOYO FORMTRACER SV-C3100 H4

NON-CONTACT INTERFEROMETRY

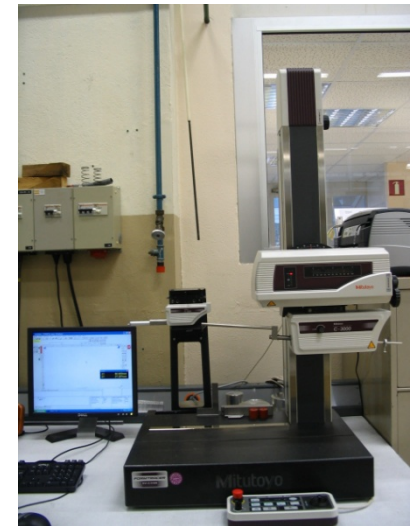
VEECO NT 3300

OTHER MEASURES

Linear measurements, straightness,
flatness, squareness, ...

PROFILE PROJECTOR

BATY R770



MME Metallurgy

Scanning Electron Microscopy

LEICA STEREOSCAN 360

LEO (Zeiss) 430

Optical Microscopy

LEICA Q600 (Quantimet) Image Processing

LEICA MZ 16 Stereomicroscope

Mechanical Testing

UTS 200, Tensile Testing at room temp.

UTS 200, Tensile Testing at 1.9 K.

Macro Hardness testing

Micro hardness testing

Siemens D-5000 X-Ray Diffractometer

Non-destructive Testing

Ultrasonic Test (USIP)

USN60

USOUND (immersion)

Radiography

Ultrasonic swinger device

